

ABSTRACT

Provided is an information processing method for optimizing a parameter related to a condition of substrate processing using a prediction model that calculates a predicted state after the substrate processing based on the parameter related to the condition of the substrate processing and an initial state of a substrate, in which optimization information, which is obtained when the parameter for processing the substrate from a first pre-processing state to a first post-processing state is optimized, is acquired, where substrate processing contents are similar, and the parameter for processing the substrate from a second pre-processing state to a second post-processing state is optimized using the acquired optimization information and the prediction model.

FIG. 2